



Docket No. 740819-418
Serial No. 09/662,004
Page 1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Kazuichiro ITONAGA et al.

Serial No. 09/662,004

Filed: September 14, 2000

For: METHOD OF FORMING INSULATING
FILM AND METHOD OF FABRICATING
SEMICONDUCTOR DEVICE

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) Group Art Unit ~~2800~~ TECHNOLOGY CENTER 2800

) Examiner: William M. Brewster

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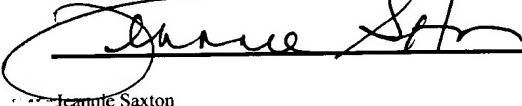
Date: December 12, 2002

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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on December 12, 2002


Jeannie Saxton

RESPONSE TO RESTRICTION/ELECTION REQUIREMENT

Commissioner for Patents
Washington, D.C. 20231

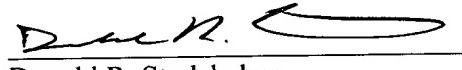
Sir:

In response to the Office Action December 3, 2002 Applicants provide the following election.

Applicant hereby elects Species I, claims 1-12, controlling a thickness and temperature of an insulating film.

Should the Examiner believe a conference would be of benefit in expediting the prosecution of the instant application, he is hereby invited to telephone counsel to arrange such a conference.

Respectfully submitted,


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